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### THE CLAIMS

What is claimed is:

5           1.    A tool for disuniting two wafers, with at least  
one of the wafers being used in fabricating substrates  
for microelectronics, optoelectronics, or optics, the  
tool comprising two gripper members for temporarily  
affixing to respective opposite faces of the wafers that  
10   are united to each other, and a disuniting control device  
suitable for moving the members relative to each other,  
wherein the disuniting control device comprises an  
actuator device for positively displacing the gripper  
members sufficiently for inducing controlled flexing in  
15   at least one of the members to assist in disuniting the  
wafers.

          2.    The tool according to claim 1, wherein one or  
each gripper member comprises a diaphragm having a  
20   plurality of orifices communicating on one side with a  
respective wafer face and on the other side with a vacuum  
source.

          3.    The tool according to claim 2, wherein the  
25   orifices are micropores.

          4.    The tool according to claim 1, wherein one or  
each gripper member comprises an electrode which has a  
different potential compared to that of a respective  
30   wafer face so as to provide temporary affixing by  
electrostatic forces.

          5.    The tool according to claim 4, wherein each  
gripper member that includes an electrode further  
35   comprises dielectric material which surrounds the  
electrode.

6. The tool according to claim 1, wherein the actuator device includes at least two actuators for acting on at least one gripper member at at least two distinct locations.

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7. The tool according to claim 1, wherein at least one gripper member comprises a body generally in the form of a plate having different degrees of elastic deformability in at least two locations.

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8. The tool according to claim 7, wherein the body is formed by assembling at least two laminations of different dimensions.

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9. The tool according to claim 7, wherein the body is formed by a plate of non-uniform thickness.

10. The tool according to claim 9, wherein the thickness of the plate varies progressively.

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11. The tool according to claim 9, wherein at least one groove is formed locally in the plate.

12. The tool according to claim 11, wherein the at least one groove extends entirely across the plate.

13. The tool according to claim 11, wherein the plate possesses at least two grooves.

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14. The tool according to claim 13, wherein the grooves are parallel.

15. The tool according to claim 1, wherein at least one gripper member includes a member for limiting flexing.

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16. The tool according to claim 15, wherein the member for limiting flexing is adjustable.

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17. The tool according to claim 11, wherein the at least one gripper member in which flexing can be induced includes a member for limiting flexing provided adjacent the groove.

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18. The tool according to claim 17, wherein the member for limiting flexing comprises a micrometer screw operating between regions of the plate that are situated on either side of the groove.

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19. The tool according to claim 1, wherein the two gripper members are mounted to pivot relative to each other, and wherein the actuator device acts at a distance from the pivot region.

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20. The tool according to claim 19, including a device for adjusting the spacing between the gripper members so as to enable united wafers of different total thicknesses to be disunited.

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21. The tool according to claim 1, wherein the actuator device comprises one or more hydraulic actuators.

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22. The tool according to claim 1, further comprising a device for measuring forces exerted by at least one of the actuators or spacing between the wafers.

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23. An assembly for disuniting a plurality of pairs of united wafers in series, the assembly comprising a plurality of tools according to claim 1, and a common actuator device engager for jointly displacing at least one gripper member of each tool.

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24. A method of disuniting two wafers, with at least one of the wafers being used in fabricating

optics, the method comprising the following steps:

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temporarily affixing two gripper members to  
respective opposite faces of the wafers; and

sufficiently displacing one of the gripper members  
relative to the other for inducing controlled flexing in  
5 at least one of the members to assist in disuniting the  
wafers.

25. The method according to claim 24, wherein the  
temporary affixing step comprises contacting the gripper  
10 members with the wafer faces by applying a vacuum.

26. The method according to claim 24, wherein the  
temporary affixing step comprises providing the gripper  
members with the wafer faces by applying electrostatic  
15 forces.

27. The method according to claim 24, wherein the  
displacement step comprises independently displacing two  
distinct regions of a single gripper member.  
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28. The method according to claim 24, wherein the  
two gripper members are mounted to pivot relative to each  
other, and the displacement step comprises mutually  
displacing regions of the gripper members that are  
25 situated at a distance from the pivot region.

29. A method of measuring the bonding energy  
between two wafers, with at least one of the wafers being  
used in fabricating substrates for microelectronics,  
30 optoelectronics, or optics, the method comprising the  
following steps:

temporarily affixing two gripper members to opposite  
faces of the wafers;

displacing one of the gripper members relative to  
35 the other sufficiently for inducing controlled flexing in  
at least one of the aid members in order to disunite the

measuring the force exerted during the displacement step or measuring the separation of the wafers while performing the disuniting operation.

- 5            30. The method of claim 29 wherein both the force exerted during the displacement step and the separation of the wafers is measured while performing the disuniting operation.